AMENDMENTS TO THE CLAIMS

Please amend the claims as follows.

1. (Currently Amended) A multiaxial sensor having a plurality of multiaxial sensor units for measuring one or more of two or more-axial force, moment, acceleration, and angular acceleration, externally applied, the plurality of multiaxial sensor units being disposed on a same plane and disposed around a center point of the multiaxial sensor at 90 degree ~~regular angular~~ intervals at the same distance from the center point, each of the multiaxial sensor units comprising:

   eight strain gauges disposed on a single plane;

   one bridge circuit constructed by connecting the strain gauges; and

   a strain generation body comprising a force receiving portion provided at a center, a fixed portion provided on an outer circumference, and an annular diaphragm portion connecting the force receiving portion and the fixed portion to each other;

   wherein the strain gauges being disposed at four positions on outer and inner edges of the diaphragm on a line perpendicular to a center line of the diaphragm, and at four positions on the outer and inner edges of the diaphragm on a line perpendicular to the line perpendicular to the center line of the diaphragm; and

   each of the strain gauges is a piezoresistive element or a strain gauge formed by sputtering.

2. (Previously Presented) A multiaxial sensor having a plurality of multiaxial sensor units for measuring one or more of three or more-axial force, moment, acceleration, and angular acceleration, externally applied,

the plurality of multiaxial sensor units being disposed on a same plane and disposed around a center point of the multiaxial sensor at regular angular intervals at the same distance from the center point,

each of the multiaxial sensor units comprising:

eight strain gauges disposed on a single plane;

two bridge circuits constructed by connecting the strain gauges; and

a strain generation body comprising a force receiving portion provided at a center, a fixed portion provided on an outer circumference, and an annular diaphragm portion connecting the force receiving portion and the fixed portion to each other;

the strain gauges being disposed at four positions on outer and inner edges of the diaphragm on a line perpendicular to a center line of the diaphragm, and at four positions on the outer and inner edges of the diaphragm on a line perpendicular to the line perpendicular to the center line of the diaphragm;

wherein each of the strain gauges is a piezoresistive element or a strain gauge formed by sputtering.

3.-7. (Canceled)

8. (Currently Amended) The multiaxial sensor according to claim [[7]] 1, wherein the multiaxial sensor units are disposed in positive and negative directions on X- and Y-axes with an origin being set at the center point.

9. (Canceled)

10. (Previously Presented) The multiaxial sensor according to claim 1, wherein the eight strain gauges of each multiaxial sensor unit are disposed at four positions on outer and inner edges

of the diaphragm on a line extending through a center point of the multiaxial sensor and a center point of each multiaxial sensor unit; and at four positions on the outer and inner edges of the diaphragm on a line perpendicular to the former line at the center point of the said multiaxial sensor unit.

11. (Previously Presented) The multiaxial sensor according to claim 1, wherein the sensor comprises a first member comprising the multiaxial sensor units each comprising the strain gauges; and a second member comprising strain generation bodies opposed to the multiaxial sensor units and comprising no strain gauges, and opposed force receiving portions of strain generation bodies are connected to each other, and multiaxial forces and moments applied between the first and second members are measured.

12. (Canceled)